

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Kazuo GOUDA et al.

Group Art Unit : 2812

Appln. No. : 10/598,372

(National Stage of PCT/JP2005/005039)

Examiner : not yet assigned

I. A. Filed : March 15, 2005

Confirmation No. : 3256

For : METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop Amendment
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Sir:

In accordance with the duty of disclosure under 37 C.F.R. §1.56 and §§1.97-1.98, Applicants hereby bring to the attention of the Examiner the following information.

The following documents were cited in an International Search Report with respect to International Patent Application No. PCT/JP2005/005039, of which the present application is the U.S. National Stage Application. A copy of the International Search Report has been filed concurrently with the present application and should thus have been brought to the attention of the Examiner.

- (1) Japanese Laid-Open Patent Publication No. 2000-187041, together with an English language Abstract of the same;

- (2) Japanese Laid-Open Patent Publication No. 2003-273370, together with an English language Abstract of the same, and patent family member U.S. Patent Application Publication No. 2003/0176071 A1;
- (3) Japanese Laid-Open Patent Publication No. 2002-198327, together with an English language Abstract the same; and
- (4) International Application Publication No. WO 01/53194 A1, together with an English language Abstract the same, patent family members European Patent Application No. EP 1 203 748 A1 and U.S. Patent No. 6,528,724 B1.

The relevance of the documents cited in the International Search Report, as ascertained with respect to the International claims by the International Examiner, is set forth in the International Search Report.

Applicants further submit the following document:

- (5) Bhavé et al, " *AN INTEGRATED, VERTICAL- DRIVE, IN-PLANE-SENSE MICROGYROSCOPE*" TRANSDUCERS '3 (IEEE, The 12th International Conference on Solid-State Sensors, Actuators Microsystems), Boston U.S., June 8-12, 2003, Pages 171-174. Applicants note that this document is cited beginning at page 1 of the specification of the above-captioned application.

Further to 37 C.F.R. §1.98 (a)(2)(ii), a copy of the U.S. patent publication is not enclosed herewith. However, if a copy is needed, the Examiner is respectfully requested to contact the undersigned.

Applicants respectfully request that the Examiner consider the above material and cite the same. Copies of above-noted foreign and international documents,

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including the noted English language Abstracts, are attached hereto, and all of the documents are listed on an attached PTO-1449 Form. The Examiner is requested to initial the appropriate spaces on the attached Form and to return a copy of the completed Form to Applicants with the next official communication in the present application.

Applicants note that an Office Action on the merits has not issued in the present application, and thus, no fee is believed necessary to ensure consideration of the submitted material.

Should the Examiner have any questions, the Examiner is invited to contact the undersigned at the below-listed telephone number.

Respectfully submitted,
Kazuo GOUDA et al.

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I.A. Filing Date
March 15, 2005

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/KC/	1	English Language Abstract of JP 2000-187041.
/KC/	2	English Language Abstract of JP 2003-273370.
/KC/	3	English Language Abstract of JP 2002-198327.
/KC/	4	Bhave et al, "AN INTEGRATED, VERTICAL- DRIVE, IN-PLANE-SENSEMICROGYROSCOPE" TRANSDUCERS '3 (IEEE, The 12 th International Conference on Solid-State Sensors, Actuators Microsystems), Boston U.S., June 8-12, 2003, Pages 171-174.

/Kin Chan Chen/

05/27/2009

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.